

Notice of References Cited	Application/Control No. 10/585,204		Applicant(s)/Patent Under Reexamination KOINUMA ET AL.	
	Examiner Sanza L. McClendon		Art Unit 1796	Page 1 of 1

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*		Document Number Country Code-Number-Kind Code	Date MM-YYYY	Name	Classification
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*	B	US-7,608,371	10-2009	Ueno et al.	430/20
*	C	US-2009/0048362	02-2009	Ueno et al.	522/2
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	K	US-			
	L	US-			
	M	US-			

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NON-PATENT DOCUMENTS

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*A copy of this reference is not being furnished with this Office action. (See MPEP § 707.05(a).)
Dates in MM-YYYY format are publication dates. Classifications may be US or foreign.